Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	13	(simulation) and (threshold same (resist adj model)) and (table)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:48
L2	115	(simulation) and (threshold same ((look-up adj table) or LUT))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:52
L3	3	(resist adj model) and (threshold same ((look-up adj table) or LUT))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 14:02
L4	3	(resist adj model) and (threshold and ((look-up adj table) or LUT))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 14:02
S1	1092	716/19	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:12
S2	783	716/21	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:12
S3	1	(716/19).ccls. and (wafer adj simulation) and (threshold adj data)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14
S4	0	(716/21).ccls. and (wafer adj simulation) and (threshold adj data)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14
S5	0	(716/21).ccls. and (wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14
S6	2	(716/19).ccls. and (wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:14

S7	2	("716"/$).ccls. and (wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:15
S8	3	(wafer adj simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 11:16
S9	39	(wafer and simulation) and (threshold same (resist adj model))	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:38
S10	3	(wafer and simulation) and (threshold same (resist adj model)) and ((look-up adj table) or LUT)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2005/11/07 13:07

IEEE Xplore RELEASE 2.1

Home | Login | Logout | Access Information | Alerts |

Welcome United States Patent and Trademark Office

Search Results BROWSE SEARCH IEEE XPLORE GUIDE

Results for "(((defect printability analysis))<in>metadata)" e-mail
Your search matched 0 documents.
A maximum of 100 results are displayed, 25 to a page, sorted by Relevance in Descending order.

» Search Options

View Session History

New Search

Modify Search

(((defect printability analysis))<in>metadata)

Check to search only within this results set

Display Format: Citation Citation & Abstract

» Key

IEEE JNL	IEEE Journal or Magazine
IEE JNL	IEE Journal or Magazine
IEEE CNF	IEEE Conference Proceeding
IEE CNF	IEE Conference Proceeding
IEEE STD	IEEE Standard

No results were found.

Please edit your search criteria and try again. Refer to the Help pages if you need assistan search.

Help Contact Us Privacy &

Indexed by Inspec

© Copyright 2005 IEEE –

IEEE Xplore RELEASE 2.1

Home | Login | Logout | Access Information | Alerts |

Welcome United States Patent and Trademark Office

☐ Search Results BROWSE SEARCH IEEE XPLORE GUIDE

Results for "(((defect) <and> (printability analysis))<in>metadata)" e-mail
Your search matched **0** documents.
A maximum of **100** results are displayed, **25** to a page, sorted by **Relevance** in **Descending** order.

» Search Options

View Session History

New Search

Modify Search

(((defect) <and> (printability analysis))<in>metadata)

Check to search only within this results set

Display Format: Citation Citation & Abstract

» Key

IEEE JNL	IEEE Journal or Magazine
IEE JNL	IEE Journal or Magazine
IEEE CNF	IEEE Conference Proceeding
IEE CNF	IEE Conference Proceeding
IEEE STD	IEEE Standard

No results were found.

Please edit your search criteria and try again. Refer to the Help pages if you need assistan search.

Help Contact Us Privacy &

Indexed by Inspec

© Copyright 2005 IEEE –

IEEE Xplore RELEASE 2.1

Home | Login | Logout | Access Information | Alerts |

Welcome United States Patent and Trademark Office

Search Results BROWSE SEARCH IEEE XPLORE GUIDE

Results for "(((defect) <and> (printability) <and> (analysis))<in>metadata)" e-mail
Your search matched **2** of **1253851** documents.
A maximum of **100** results are displayed, **25** to a page, sorted by **Relevance** in **Descending** order.

» Search Options

View Session History

New Search

Modify Search

(((defect) <and> (printability) <and> (analysis))<in>metadata)

Check to search only within this results set

Display Format: Citation Citation & Abstract

» Key

IEEE JNL	IEEE Journal or Magazine
IEE JNL	IEE Journal or Magazine
IEEE CNF	IEEE Conference Proceeding
IEE CNF	IEE Conference Proceeding
IEEE STD	IEEE Standard

Select **Article Information**

1. **A defect-to-yield correlation study for marginally printing reticle defects i manufacture of a 16Mb flash memory device**
Erhardt, J.; Phan, K.; Backe, E.; Tran, Q.; Fletcher, B.; Hopper, C.B.; Peterson
Advanced Semiconductor Manufacturing Conference and Workshop, 2000 IEE
12-14 Sept. 2000 Page(s):96 - 102
Digital Object Identifier 10.1109/ASMC.2000.902566
AbstractPlus | Full Text: PDF(676 KB) **IEEE CNF**

2. **Correlation between printability and visibility of defects in EUV mask blar**
Ito, M.; Tezuka, Y.; Terasawa, T.; Tomie, T.;
Microprocesses and Nanotechnology Conference, 2003. Digest of Papers. 20(
29-31 Oct. 2003 Page(s):278 - 279
AbstractPlus | Full Text: PDF(193 KB) **IEEE CNF**

Help Contact Us Privacy &

Indexed by Inspec

© Copyright 2005 IEEE –

IEEE Xplore RELEASE 2.1

Home | Login | Logout | Access Information | Alerts |

Welcome United States Patent and Trademark Office

BROWSE SEARCH IEEE XPLORE GUIDE

Search Results

Results for "(((resist model) <and> (threshold) <and> (look-up table))<in>metadata)" e-mail
Your search matched **0** documents.
A maximum of **100** results are displayed, **25** to a page, sorted by **Relevance** in **Descending** order.

» Search Options

View Session History

New Search

Modify Search

(((resist model) <and> (threshold) <and> (look-up table))<in>metadata)

Check to search only within this results set

Display Format: Citation Citation & Abstract

» Key

IEEE JNL	IEEE Journal or Magazine
IEE JNL	IEE Journal or Magazine
IEEE CNF	IEEE Conference Proceeding
IEE CNF	IEE Conference Proceeding
IEEE STD	IEEE Standard

No results were found.

Please edit your search criteria and try again. Refer to the Help pages if you need assistan search.

Help Contact Us Privacy &

Indexed by Inspec

© Copyright 2005 IEEE –

Results for "(((resist model) <and> (threshold) <and> (lut))<in>metadata)" e-mail
Your search matched **0** documents.
A maximum of **100** results are displayed, **25** to a page, sorted by **Relevance** in **Descending** order.

» Search Options

View Session History

New Search

Modify Search

(((resist model) <and> (threshold) <and> (lut))<in>metadata)

☐ Check to search only within this results set

Display Format: ◉ Citation ○ Citation & Abstract

» Key

IEEE JNL	IEEE Journal or Magazine
IEE JNL	IEE Journal or Magazine
IEEE CNF	IEEE Conference Proceeding
IEE CNF	IEE Conference Proceeding
IEEE STD	IEEE Standard

No results were found.

Please edit your search criteria and try again. Refer to the Help pages if you need assistan search.

Indexed by Inspec

© Copyright 2005 IEEE –